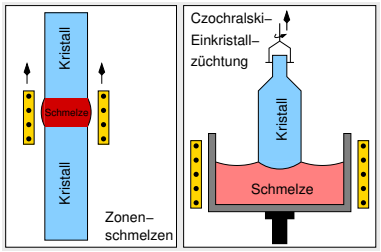
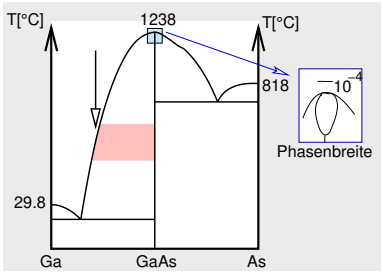
## 2.4.3. Herstellung von Halbleitern

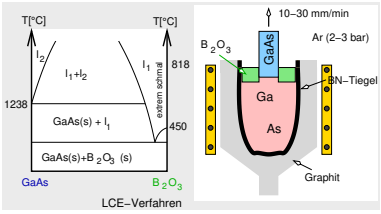
### 2.4.3.1. Substratherstellung




Kristallzüchtung

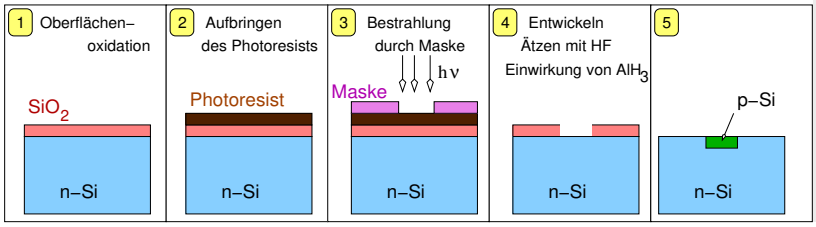



PD GaAs

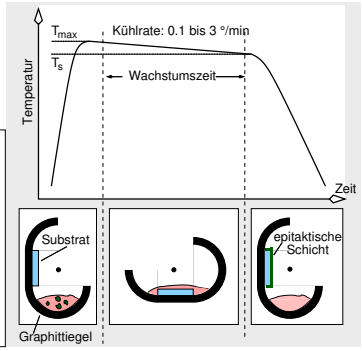



LEC-Verfahren

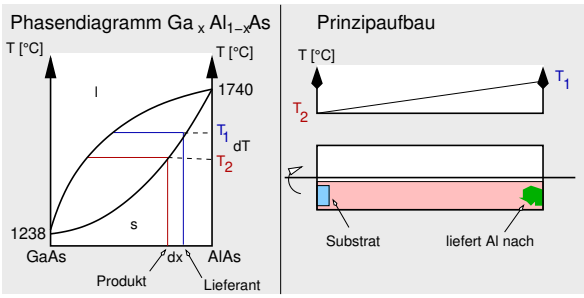
### 2.3.3.2. Depositionsverfahren/Herstellung epitaktischer Schichten



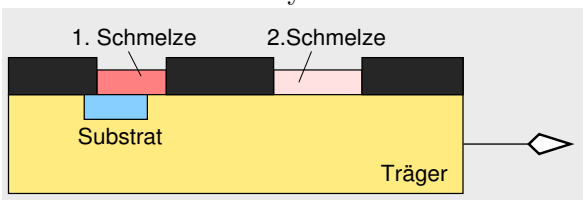

Diffusionsverfahren



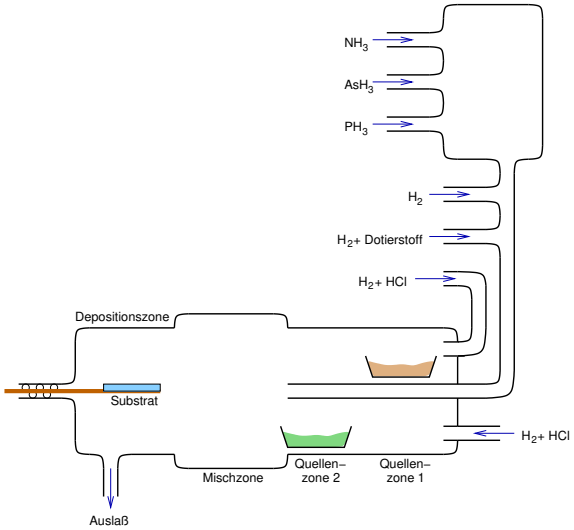

LPE II: Tipping



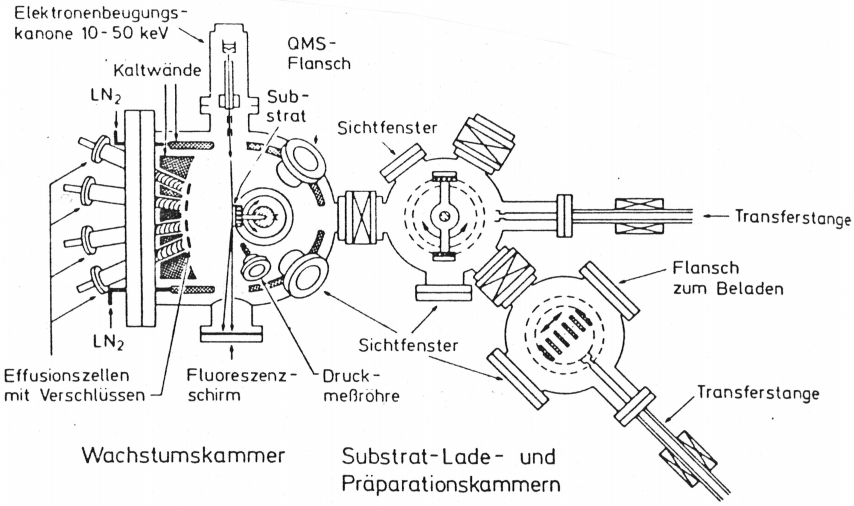

LPE III: Steady-State-Technik




LPE IV: Sliding




Chemical Vapor Deposition (CVD)




Molekularstrahl-Epitaxie (MBE)